

Form PTO 4449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE			ATTY. DOCKET NO. MI22-1828		SERIAL NO. 10/071,425	
<div style="display: flex; align-items: center;"> <div style="border: 1px solid black; border-radius: 50%; padding: 10px; text-align: center; margin-right: 10px;"> NOV 02 2005 PATENT & TRADEMARK OFFICE </div> <div> LIST OF ART CITED BY APPLICANT (Use several sheets if necessary) </div> </div>					APPLICANT: Terry L. Gilton et al.			
					FILING DATE February 8, 2002		GROUP 2813	

U.S. PATENT DOCUMENTS							
Examiner's Initials	AA	Document Number	Date	Name	Class	Subclass	Filing Date if Appropriate
	AA						
	AB						
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	AH						
	AI						

FOREIGN PATENT DOCUMENTS								
	AJ	Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AJ							
	AK							
	AL							

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)		
TSP	AM	Lee et al., <i>Lithographic Properties of SiN_x and Se₇₅Ge₂₅ Thin Films as the Low-Energy Ion-Beam Resist</i> , 5 th International Conference on Properties and Applications of Dielectric Materials, Seoul, Korea
	AN	(May 25-30, 1997) pp. 635-638.
AO		
<div style="display: flex; justify-content: space-between;"> <div> EXAMINER </div> <div> DATE CONSIDERED 5/29/05 </div> </div>		

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.